



**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Tomoe MIYAZAWA et al.

Application No.: 10/695,773

Docket No.: 117641

Filed: October 30, 2003

For: MALEIC ACID AND ETHYLENE UREA CONTAINING FORMULATION FOR  
REMOVING RESIDUE FROM SEMICONDUCTOR SUBSTRATE AND  
METHOD FOR CLEANING WAFER

**REQUEST FOR CORRECTION OF PALM RECORDS**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records. A Supplemental Application Data Sheet is attached.

Respectfully submitted,

James A. Oliff  
Registration No. 27,075

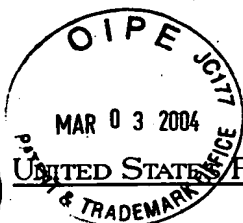
Thomas J. Pardini  
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JAO:TJP/mlo

Date: March 3, 2004

**OLIFF & BERRIDGE, PLC**  
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<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>
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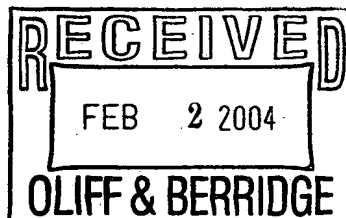
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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/695,773	10/30/2003	2812	860	117641		25	2

CONFIRMATION NO. 6898

25944

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FILING RECEIPT



\*OC000000011794644\*

Date Mailed: 01/30/2004

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

**Applicant(s)**

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Chiyoda-KU

**Assignment For Published Patent Application**

NISSAN CHEMICAL INDUSTRIES, LTD., Tokyo, JAPAN;

**Domestic Priority data as claimed by applicant****Foreign Applications**

If Required, Foreign Filing License Granted: 01/29/2004

Projected Publication Date: To Be Determined - pending completion of Missing Parts

Non-Publication Request: No

Early Publication Request: No

**Title**

Maleic acid and ethylene urea containing formulation for removing residue from semiconductor substrate and method for cleaning wafer